

Applicant(s):

Finarov, Moshe

Assignee: \ P

Nova Measuring Instruments

Title:

APPARATUS FOR OPTICAL INSPECTION OF WAFERS DURING POLISHING

Serial Strianens

FEB 0 5 1999

09/047,944

Filed:

March 25, 1998

Examiner:

E. Morgan

Group Art Unit:

3723

Docket No.:

M-3417-1CUS

San Jose, California February 5, 1999z

## ASSISTANT COMMISSIONER FOR PATENTS

**BOX CPA** 

Washington, D. C. 20231

## INFORMATION DISCLOSURE STATEMENT

## Dear Sir:

Pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98, Applicant brings the following documents (copies enclosed) to the Examiner's attention in the above-captioned application.

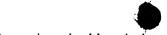
- 1. USP 5,658,183 issued 08/19/97 to Sandhu et al.
- 2. USP 5,486,129 issued 01/23/96 to Sandhu et al.
- 3. USP 5,643,060 issued 07/01/97 to Sandhu et al.
- 4. USP 5,730,642 issued 03/24/98 to Sandhu et al.
- 5. USP 5,762,537 issued 06/09/98 to Sandhu et al.
- 6. USP 5,700,180 issued 12/23/97 to Sandhu et al.

A PTO form 1449 listing these documents is enclosed.

Citation of the above documents shall not be construed as:

- 1. an admission that the documents are necessarily prior art with respect to the instant invention;
- 2. a representation that a search has been made, other than as described above; or

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3. an admission that the information cited herein is, or is considered to be, material to patentability as defined in § 1.56(b).

**EXPRESS MAIL LABEL NO:** 

EL 252 576 876 US

Respectfully submitted,

David W. Heid

Attorney for Applicant(s)

Reg. No. 25,875